

## Academic Degrees

<b>Degree</b>	<b>Name</b>	<b>Doctor's Thesis</b>
Doctor of Engineering	<b>Akihisa Nagano</b> (University of Hyogo)	<i>Studies on laser-produced plasma EUV source by using Lithium and Xenon</i>
Doctor of Engineering	<b>Yoshitaka Sawa</b> (University of Hyogo)	<i>Fabrication of High Hardness Electroformed Micro Mold by LIGA Process, and Research on the Its Application</i>

<b>Degree</b>	<b>Name</b>	<b>Master's Thesis</b>
Master of Engineering	<b>Tomoaki Inoue</b> (University of Hyogo)	<i>Study on a high-repetition-rate pulse laser plasma soft x-ray source system and its applications</i>
Master of Engineering	<b>Saki Kondo</b> (University of Hyogo)	<i>Proposal of 3D Micro-chemical Chip and Its Application to ELISA</i>
Master of Engineering	<b>Tomoya Omukai</b> (University of Hyogo)	<i>High Density Cell Cultivation of Hep G2 Using High Aspect Ratio Micro Scaffold</i>
Master of Engineering	<b>Munehiko Kato</b> (University of Hyogo)	<i>Investigation of fabrication Process of Flexible Electrode for Neural Interface</i>
Master of Engineering	<b>Naoki Sakagami</b> (University of Hyogo)	<i>Development of EUV Interference Lithographic Exposure Tool and Fine Pattern Replication</i>
Master of Engineering	<b>Yoshito Kamaji</b> (University of Hyogo)	<i>Definition of Pit-Type Phase-Defects Criteria between Printable and Non Printable of EUV Mask</i>
Master of Engineering	<b>Kei Takase</b> (University of Hyogo)	<i>Refinement of EUV Mask Defects Observation Utilizing EUV Microscope</i>
Master of Engineering	<b>Yuta Okayama</b> (University of Hyogo)	<i>Fabrication of High Luminance Ultraviolet Range Light Guide Plate</i>
Master of Engineering	<b>Masaru Setomoto</b> (University of Hyogo)	<i>Fabrication and Estimation of Microcoil Using X-ray Lithography</i>
Master of Engineering	<b>Naoki Takahashi</b> (University of Hyogo)	<i>Fabrication of Diffraction Gratings for Talbot Interferometer Using New Carbon X-ray Mask</i>
Master of Engineering	<b>Hiroaki Miyake</b> (University of Hyogo)	<i>Fabrication and Estimation of Micro Capacitive Inclination Sensors by Resin Molding</i>